

Abstract

SUBSTRATE TREATING APPARATUS

5 Provided is a substrate treating apparatus comprises an equipment front end
module for carrying in a substrate for a treatment and carrying out the substrate
which has been treated, a processing module for processing the substrate, a transfer
chamber for carrying in and out the substrate to the processing module and
controlling an oxygen concentration, and a loadlock chamber positioned between the
10 equipment front and end module and the transfer chamber for providing a path for
the substrate to be moved and controlling an oxygen concentration.

FIG. 2

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